IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Thakar et al

JAN 2 1 2004

Customer Service Center

Serial No.

10/645,032

**Initial Examination Division** 

Filed:

08/21/2003

Docket: TI-32822.1

For:

POLYSILICON PROCESSING USING AN ANTI-REFLECTIVE

DUAL LAYER HARDMASK FOR 193 nm LITHOGRAPHY

Commissioner for Patents PO Box 1450 Alexandria, Virginia 22313-1450

Sir:

## PRELIMINARY AMENDMENT

On page 1 of the Specification, before the first paragraph, please insert the following:

-- This application is a Division of 09/939,259 filed 08/24/2001, now U.S. 6,624,068. –

Respectfully submitted,

Gary C. Honeycutt, Reg. No. 20,250

Atorney for Applicant

972-470-0130

1-17-04